

Title (en)
SEMICONDUCTOR DEVICE

Title (de)
HALBLEITERBAUELEMENT

Title (fr)
DISPOSITIF À SEMICONDUCTEUR

Publication
EP 3985749 B1 20230816 (EN)

Application
EP 20209712 A 20201125

Priority
CN 202011088594 A 20201013

Abstract (en)
[origin: EP3985749A1] A semiconductor device includes a substrate, a first dielectric layer, a second dielectric layer, and a third dielectric layer. The first dielectric layer is disposed on the substrate, around a first metal interconnection. The second dielectric layer is disposed on the first dielectric layer, around a via and a second metal interconnection. The second metal interconnection directly contacts the first metal interconnection. The third dielectric layer is disposed on the second dielectric layer, around a first magnetic tunneling junction (MTJ) structure and a third metal interconnection. The third metal interconnection directly contacts the first MTJ structure and the second metal interconnection, and the first MTJ structure directly contacts the via.

IPC 8 full level
H10N 50/10 (2023.01); **H10N 50/80** (2023.01); **H10N 59/00** (2023.01)

CPC (source: EP US)
G11C 11/161 (2013.01 - EP); **H10B 61/00** (2023.02 - EP); **H10B 61/22** (2023.02 - US); **H10N 50/10** (2023.02 - EP US); **H10N 50/80** (2023.02 - US); **H10N 50/85** (2023.02 - US)

Designated contracting state (EPC)
AL AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO RS SE SI SK SM TR

DOCDB simple family (publication)
EP 3985749 A1 20220420; **EP 3985749 B1 20230816**; CN 114361201 A 20220415; EP 4236665 A2 20230830; EP 4236665 A3 20231101; US 11700775 B2 20230711; US 11957061 B2 20240409; US 2022115587 A1 20220414; US 2023292627 A1 20230914

DOCDB simple family (application)
EP 20209712 A 20201125; CN 202011088594 A 20201013; EP 23180030 A 20201125; US 202017090859 A 20201105; US 202318200592 A 20230523